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WHAT IS CLAIMED IS:

1. A method for manufacturing a semiconductor device comprising steps of:

5 fixing semiconductor chips onto a substrate;

covering the semiconductor chips fixed onto the substrate with a common resin layer;

gluing an adhesive sheet onto the resin layer;

cutting the substrate and the resin layer in a state that the adhesive sheet is glued to the resin layer; and

measuring the semiconductor devices in a state that the adhesive sheet is glued to the resin layer.

10 2. A method for manufacturing a semiconductor device according to claim 1,

15 wherein the substrate and the resin layer is cut from the reverse surface of the substrate in a state that the adhesive sheet is glued to the resin layer.

20 3. A method for manufacturing a semiconductor device according to claim 1,

wherein the substrate and the resin layer which are cut are integrally supported by the adhesive sheet.

25 4. A method for manufacturing a semiconductor device

according to claim 1,

wherein the substrate and the resin layer is cut by performing dicing in a state that the adhesive sheet is glued to the resin layer.

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5. A method for manufacturing a semiconductor device according to claim 1,

wherein external electrodes are provided on the reverse surface of the substrate and electrically connected to the semiconductor chips.

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6. A method for manufacturing a semiconductor device according to claim 1, further comprising a step of:

flattening the surface of the resin layer after covering the semiconductor chips with the resin layer.

7. A method for manufacturing a semiconductor device according to claim 1,

wherein the circumferential edge of the adhesive sheet 20 is fixed to a metal frame.

8. A method for manufacturing a semiconductor device according to claim 7,

wherein a plurality of the substrates are glued to the 25 adhesive sheet.

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9. A method for manufacturing a semiconductor device according to claim 1, further comprising steps of:

fixing semiconductor chips onto a substrate;

5 covering the semiconductor chips fixed onto the substrate with a common resin layer;

gluing an adhesive sheet onto the resin layer;

cutting the substrate and the resin layer in a state that the adhesive sheet is glued to the resin layer;

10 measuring the semiconductor devices in a state that the adhesive sheet is glued to the resin layer;

peeling the resin layer from the adhesive sheet after performing the measurement of the semiconductor devices; and

directly storing the semiconductor device peeled from  
15 the adhesive sheet in a carrier tape.

10. A method for manufacturing a semiconductor device according to claim 9,

wherein the substrate and the resin layer is cut from  
20 the reverse surface of the substrate in a state that the adhesive sheet is glued to the resin layer.

11. A method for manufacturing a semiconductor device according to claim 9,

25 wherein the substrate and the resin layer which are cut

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are integrally supported by the adhesive sheet.

12. A method for manufacturing a semiconductor device according to claim 9,

5 wherein the substrate and the resin layer is cut by performing dicing in a state that the adhesive sheet is glued to the resin layer.

10 13. A method for manufacturing a semiconductor device according to claim 9,

wherein external electrodes are provided on the reverse surface of the substrate and electrically connected to the semiconductor chips.

15 14. A method for manufacturing a semiconductor device according to claim 9, further comprising a step of:

flattening the surface of the resin layer after covering the semiconductor chips with the resin layer.

20 15. A method for manufacturing a semiconductor device according to claim 9,

wherein the circumferential edge of the adhesive sheet is fixed to a metal frame.

25 16. A method for manufacturing a semiconductor device

according to claim 10,

wherein a plurality of the substrates are glued to the adhesive sheet.

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